

INFORMATION DISCLOSURE CITATION PTO-1449 SHEET 1 OF 2		ATTY. DOCKET NO.	SERIAL NO.
		P128-US	Not Yet Assigned
		APPLICANT Jonathan Doan	
		FILING DATE Herewith	GROUP Not Yet Assigned

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
EC	Published Patent App No.US2002/0132 389 A1	09/19/02	Patel, et al.			
	Published Patent App No.US2003/0166 342A1	09/04/03	Chinn, et al.			
	Published Patent App No.US2003/0036 215 A1	02/20/03	Reid			
	Published Patent App No.US2003/0124 462A1	07/03/03	Miller			
	6,396,975B1	05/28/02	Wood, et al.			
	6,376,787,B1	04/23/02	Martin, et al.			
	5,709,802	01/20/98	Furuhasha, et al.			
	6,024,801	02/15/00	Wallace, et al.			
	6,492,309B1	12/10/02	Behr, et al.			
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EC	S. Mubassar Ali, et al., USE OF THERMAL CYCLING TO REDUCE ADHESION OF OTS COATED MEMS CANTILEVERS, 2003, pp. 151-162.
	Michael R. Houston, et al., SELF-ASSEMBLED MONOLAYER FILMS AS DURABLE ANTI-STICKTION COATINGS FOR POLYSILICON MICROSTRUCTURES, 1996, pp.42-47.
↓	In-Ha Sung, et al., MICRO/NANO-TRIBOLOGICAL CHARACTERISTICS OF SELF-ASSEMBLED MONOLAYER AND ITS APPLICATION IN NANO-STRUCTURE FABRICATION, 2003, pp.808-818
	<i>Eric Ann</i> <i>12/6/05</i>

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SHEET 2 OF 2			

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
EC	6,259,551B1	07/10/01	Jacobs			
	5,936,758	08/10/99	Fisher, et al.			
	5,939,785	08/17/99	Klonis, et al.			
	6,204,085B1	03/20/01	Strumpell, et al.			
	5,512,374	04/30/96	Wallace, et al.			
↓	6,464,892B2	10/15/02	Moon, et al.			

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EC	Uthara Srinivasan, et al., LUBRICATION OF POLYSILICON MICROMECHANISMS WITH SELF-ASSEMBLED MONOLAYERS, 1998, pp.156-161.
	Uthara Srinivasan, et al., ALKYLTRICHLOROSILANE-BASED SELF-ASSEMBLED MONOLAYER FILMS FOR STICKTION REDUCTION IN SILICON MICROMACHINES, 1998, pp.252-260.
↓	M.P. de Boer et al., ADHESION, ADHESION HYSTERESIS AND FRICTION IN MEMS UNDER CONTROLLED HUMIDITY AMBIENTS, 1998, pp.127-129.
	C. G. Khan Malek, et al., ADHESION PROMOTION BETWEEN POLY(METHYL METHACRYLATE) AND METALLIC SURFACES FOR LIGA EVALUATED BY SHEAR STRESS MEASUREMENTS, 1998, pp.3543-3546.

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<p style="text-align: center;">INFORMATION DISCLOSURE CITATION</p> <p style="text-align: center;">APR 27 2005</p> <p style="text-align: center;">PTO-1449</p> <p style="text-align: center;">SHEET 1 OF 2</p>		ATTY. DOCKET NO. P128-US		SERIAL NO. 10/766,776		
		APPLICANT Doan, et al.				
		FILING DATE 1/27/04		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>EC</i>	5,939,785	8/17/99	Klonis, et al.			
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	2004/0100677	5/27/04	Huibers, et al.			
	2004/0125346	7/1/04	Huibers			
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
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<i>EC</i>	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.					
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKTION COATINGS FOR MEMS, Pgs 1-6.					
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	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.					
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.					
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.					
<i>V</i>	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICKTION REDUCTION, 1997 ieee, Pgs. 1399-1402.					
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V	6,086,726	7/11/00	Renk, et al.				
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